

ABSTRACT OF THE DISCLOSURE

Apparatus and methods are disclosed for storing a plurality of supports having a plurality of chemical compounds bound to the surfaces of the supports. In the apparatus, a mechanism for diffusively introducing pressurized gas into the apparatus is in fluid communication with an outlet element comprising a plurality of openings. A holding chamber for the supports is in fluid communication with the outlet element. The outlet element and the holding chamber are disposed such that gas flow through the chamber is substantially uniform and unidirectional. The holding chamber comprises an opening sufficient to permit movement of the supports to and from the holding chamber and comprises a plurality of holding elements for holding the supports.

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